

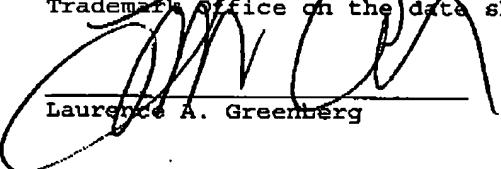
Attorney's Docket No. MUH - 12818

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CERTIFICATION OF MAILING OR TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 or facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.


Laurence A. GreenbergMay 15, 2006
DateIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/675,049 Confirmation No.: 5871
Applicant : Ioannis Dotsikas
Filed : September 30, 2003
Title : Method and Furnace for the Vapor Phase Deposition of Components onto Semiconductor Substrates with a Variable Main Flow Direction of the Process Gas
Art Unit : 2818
Examiner : Dung Anh Le
Customer No. : 24131

A M E N D M E N T

Mail Stop Fee Amendment
Hon. Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office action dated February 16, 2006,
kindly amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 9 of this paper.